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Tae Kyung Won et al.

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109/938435  
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**U.S. PATENT DOCUMENTS**

Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
CJP	A1	5,534,072	07/09/96	Mizuno et al.	—	—	
CJP	A2	5,844,205	12/01/98	White et al.	—	—	
CJP	A3	5,977,519	11/02/99	Sorensen et al.	—	—	
CJP	A4	6,225,601 B1	05/01/01	Beer et al.	—	—	
	A5						
	A6						

**FOREIGN PATENT DOCUMENTS**

		Document Number	Date	Country	Class	Subclass	Translation Yes No
	B1						
	B2						
	B3						

**OTHER ART** (Including Author, Title, Date, Pertinent Pages, Etc.)

CJP	C1	Hajjar et al., entitled "Structural and Electrical Properties of Polycrystalline Silicon Films Deposited by Low Pressure Chemical Vapor Deposition with and Without Plasma Enhancement," Journal of Electronic Materials, Vol. 15, No. 5, 1986					
	C2						
	C3						
	C4						

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EXAMINER	DATE CONSIDERED
CJP	11/8/02
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	